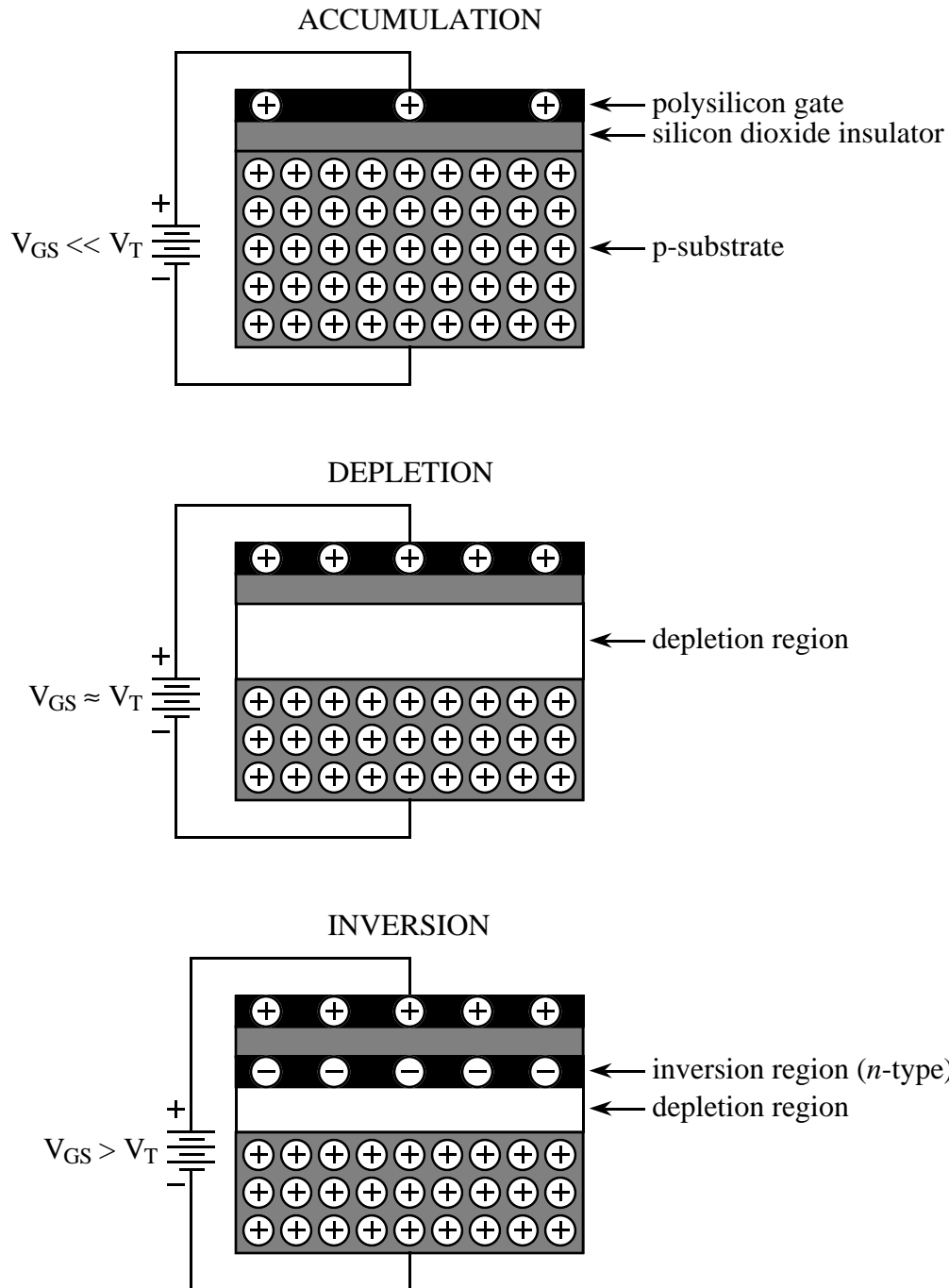


# MOSFET Device Operation



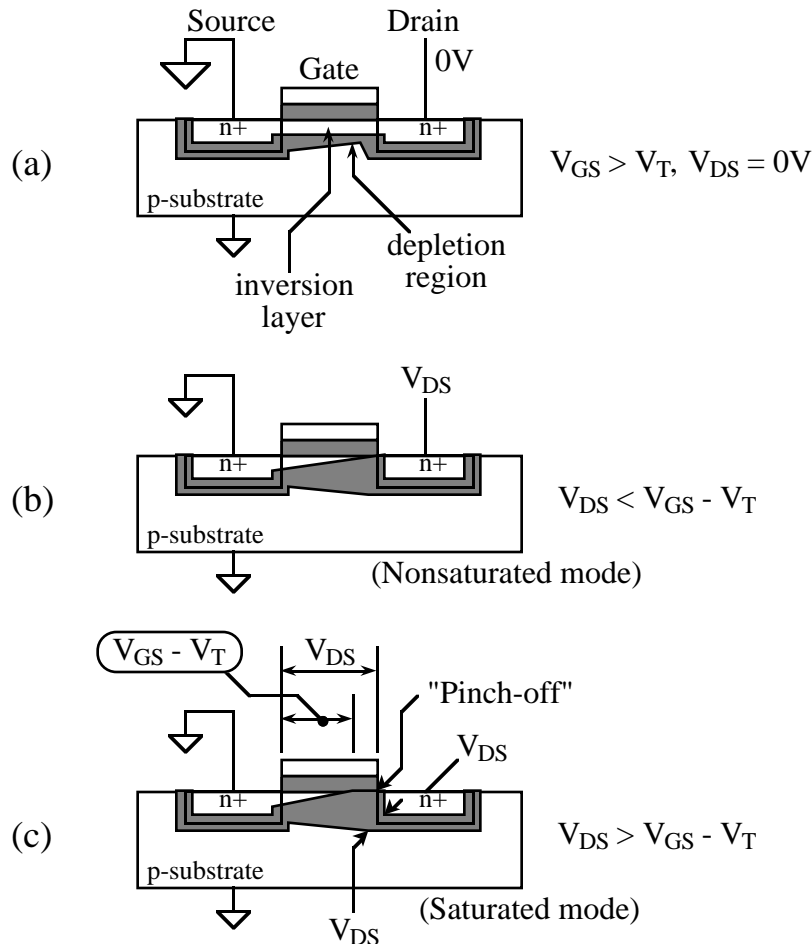
Enhancement-mode nMOS transistor cross-section

Holes are repelled from the gate by positive  $V_{GS}$  (nMOSFET)

At the onset of INVERSION, electrons attracted under the gate to form channel.

For a depletion-mode nMOS, area under gate is actually a lightly doped n-type material so that threshold voltage is  $< 0V$ .

## MOSFET Structure versus Bias



Cross-section (a): potential in channel same everywhere because  $V_{GS} = V_{GD}$ , channel "depth" same everywhere since  $V_{GS} > V_T$  and  $V_{GD} > V_T$

Cross-section (b): Depth of channel varies somewhat linearly with  $V_{GS}$  and  $V_{DS}$ . As  $V_{DS}$  is increased, the drain-side of channel (just beneath the gate) becomes "pinched" because  $V_{GD}$  becomes less and less.

Cross-section (c): Here the current depends only on  $V_{GS}$  and not  $V_{DS}$  (if we neglect channel-length modulation) and the channel becomes completely pinched-off near the drain. With  $V_{DS} > V_{GS} - V_T$  but  $V_S = 0V$ , then  $V_D > V_G - V_T$  and hence,  $V_T > V_{GD}$ , i.e.,  $V_{gate-to-drain}$  is less than the threshold voltage.

How does conduction occur *after* "pinch-off"? Electrons enter channel from source, then are swept across depletion region near drain by the positive drain voltage with respect to source ( $V_{DS}$ ).

## MOSFET Threshold Voltage

$$V_T = V_{T\text{-MOS}} + V_{fb} \quad (V_{T\text{-MOS}} \text{ is positive for } n\text{MOS, negative for } p\text{MOS})$$

$V_{T\text{-MOS}}$  — ideal threshold voltage for a MOS capacitor (the capacitor formed between the gate and substrate)

$V_{fb}$  — Flatband voltage

$$V_{T\text{-MOS}} = 2\phi_b + \frac{Q_b}{C_{ox}} \quad (\text{Note: "Q}_b\text{" sometimes referred to as "Q}_{bo}\text{"})$$

$$\phi_b = \frac{kT}{q} \ln \left( \frac{N_A}{n_i} \right) \Leftarrow \text{bulk Fermi potential}$$

$C_{ox}$  = oxide capacitance, inversely proportional to oxide thickness  $\left( C_{ox} = \frac{\epsilon_{ox}}{t_{ox}} \right)$

$$Q_b = \sqrt{2\epsilon_{si} \cdot q \cdot N_A \cdot 2\phi_b} \quad \Leftarrow \text{bulk charge term (total charge stored in depletion layer), } p\text{-substrate in this case}$$

Bulk potential — potential difference between Fermi level in intrinsic semiconductor and Fermi level in doped semiconductor

Fermi level is the average energy level in a material. For intrinsic materials, it is halfway between the valence band and conduction band.

$p$ -type  $\Rightarrow$  Fermi level closer to valence band

$n$ -type  $\Rightarrow$  Fermi level closer to conduction band

Other Constants (see text for values):

$k$  = Boltzmann's constant (eV/K, J/K)

$q$  = Electronic charge (coulombs)

$T$  = temperature ( $^{\circ}$ K)

$N_A$  = carrier density in doped semiconductor

$n_i$  = intrinsic carrier concentration in Silicon

$\epsilon_{si}$  = permittivity of Silicon =  $\epsilon_r \cdot \epsilon_0$

$\epsilon_r$  = 11.7 (relative Silicon permittivity)

$\epsilon_0$  (permittivity of free space)

## MOSFET Threshold Voltage (continued)

$$V_{fb} = \phi_{ms} - \frac{Q_{fc}}{C_{ox}} \quad (\phi_{ms} = \text{gate work function, } Q_{fc} \text{ sometimes referred to as } Q_{ss})$$

$Q_{fc} \Rightarrow$  fixed charge due to surface states which arise due to imperfections in silicon oxide interface and doping

$\phi_{ms} \Rightarrow$  gate work function which is the work function difference between the gate material and substrate

$$\phi_{ms} = - \left( \frac{E_g}{2q} + \phi_b \right)$$

$E_g \Rightarrow$  Bandgap energy of Silicon (temperature dependent)

$\phi_b \Rightarrow$  bulk Fermi potential

Note:  $E_g$  is actually in electron volts,  $1\text{eV} = 1q \cdot 1\text{V}$ , so "q" 's in  $\phi_{ms}$  expression cancel out.

Two common techniques for increasing the native threshold voltage of a MOS device:

- (1) Vary the doping concentration at the silicon-insulator interface through ion implantation (in process step called "threshold adjustment")

⇒ affects  $Q_{fc}$  ( $Q_{ss}$ , surface state charge)

- (2) Use different insulating material for gate

⇒ affects  $C_{ox}$

Between transistors, use very thick oxide ( $\gg t_{ox}$ ) to increase threshold voltage so that substrate surface does not become inverted through normal circuit voltage (obviously you do not want signal wire voltages and  $V_{DD}$  lines inverting substrate). This keeps transistors electronically isolated from each other.

**Example  $V_T$  calculation:** Calculate the native threshold voltage for an  $n$ -transistor at  $300^\circ\text{K}$  for a process with a Si substrate with  $N_A = 1.80 \times 10^{16}\text{cm}^{-3}$ , a  $\text{SiO}_2$  gate oxide with thickness  $200\text{\AA}$ . (Assume  $\phi_{ms} = -0.9\text{V}$ ,  $Q_{fc} = 0\text{C}$ .)

$$\phi_b = 0.02586 \ln \frac{1.80 \times 10^{16}}{1.45 \times 10^{10}} = 0.36\text{V};$$

$$\text{note } \frac{kT}{q} = 0.02586\text{V @ } T = 300^\circ\text{K}$$

with

$$C_{ox} = \frac{3.9 \times 8.85 \times 10^{-14}}{0.2 \times 10^{-5}} = 1.726 \times 10^{-7} \frac{\text{Farads}}{\text{cm}^2}$$

resulting in

$$V_T = \phi_{ms} + \frac{\sqrt{2\epsilon_{si}qN_A 2\phi_b}}{C_{ox}} + 2\phi_b = (-0.9 + 0.384 + 0.72)\text{V} = 0.16\text{V}$$

This device has a *very* low threshold voltage.

## Substrate (bulk) bias effect on Threshold Voltage

For  $n$ MOS, substrate usually tied to ground. However, if  $V_{SB}$  (source-to-bulk)  $\neq 0V$ , the threshold equations become:

$$V_T = V_{fb} + 2\phi_b + \frac{\sqrt{2\epsilon_{si}qN_A(2\phi_b + |V_{SB}|)}}{C_{ox}}$$

$$V_T = V_{TO} + \gamma \left( \sqrt{2\phi_b + |V_{SB}|} - \sqrt{2\phi_b} \right)$$

where  $V_{TO}$  is threshold voltage when  $V_{SB} = 0V$  and  $\gamma$  is a constant which describes substrate bias effect.

$$\gamma = \frac{t_{ox}}{\epsilon_{ox}} \sqrt{2\epsilon_{si}qN_A} = \frac{1}{C_{ox}} \sqrt{2\epsilon_{si}qN_A}$$

Values of  $\gamma$  usually range from  $(0.4 \text{ to } 1.2)V^{1/2}$ .

In SPICE,  $\gamma = \text{GAMMA}$ ,  $V_{TO} = \text{VTO}$ ,  $N_A = \text{NSUB}$ ,  $\phi_s = 2\phi_b$  is PHI.

**Example** of substrate bias effect on threshold voltage: With  $N_A = 3 \times 10^{16} \text{cm}^{-3}$ ,  $t_{ox} = 200 \text{\AA}$ ,  $\epsilon_{ox} = 3.9 \times 8.85 \times 10^{-14} \text{F/cm}$ ,  $\epsilon_{si} = 11.7 \times 8.85 \times 10^{-14} \text{F/cm}$ , and  $q = 1.6 \times 10^{-19} \text{Coulomb}$

$$\gamma = \frac{0.2 \times 10^{-5}}{3.9 \times 8.85 \times 10^{-14}} \sqrt{2 \times 1.6 \times 10^{-19} \times 11.7 \times 8.85 \times 10^{-14} \times 3 \times 10^{16}} = 0.57 V^{1/2}$$

$$\phi_b = 0.02586 \ln \frac{3 \times 10^{16}}{1.5 \times 10^{10}} = 0.375 V$$

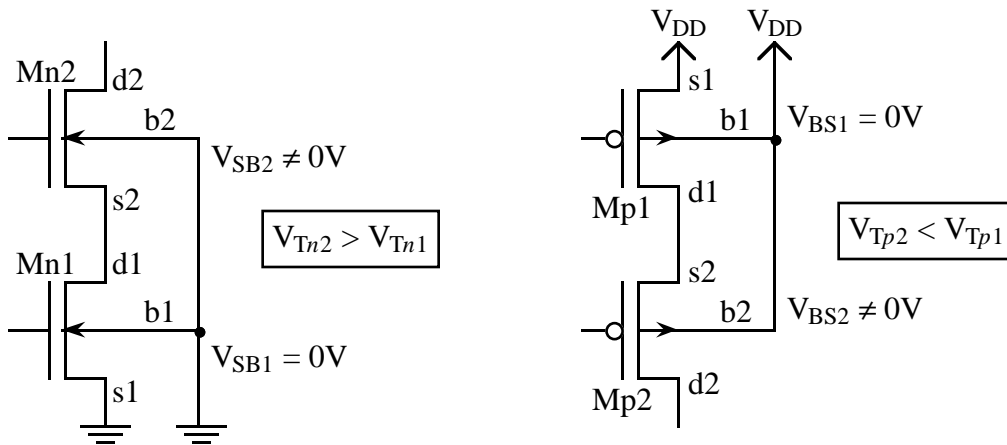
At a  $V_{SB} = 2.5V$ ,

$$V_T = V_{TO} + 0.57(\sqrt{0.75 + 2.5} + \sqrt{0.75})$$

$$V_T = V_{TO} + 0.53V$$

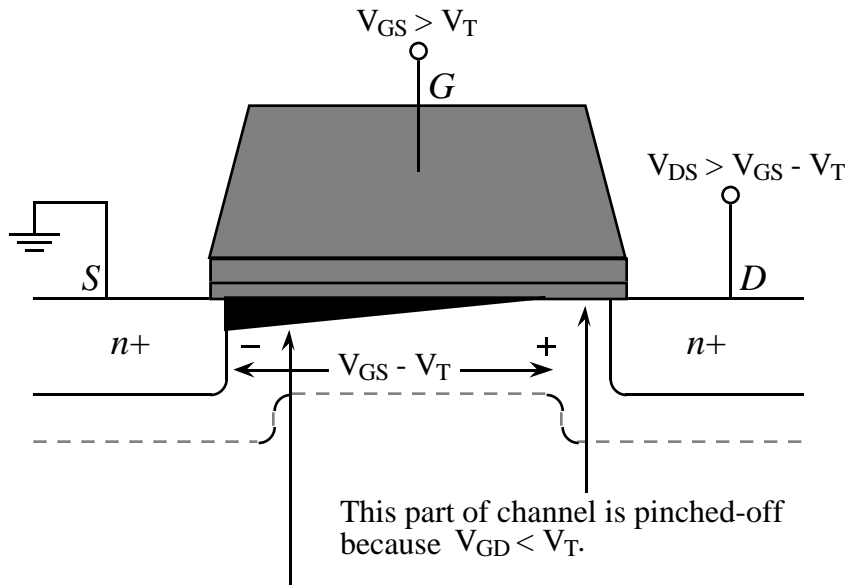
In analog designs it is quite common to use substrate bias to shift threshold voltage.

**Note:** When connecting devices in series,  $V_T$  of top device will increase if  $V_B$  tied to appropriate rail because  $V_{SB}$  is not zero.



Actual shift in threshold voltage due to the above arrangement is very small.

## Revisit operation under Saturation



Current in the induced channel is constant because voltage drop is fixed at  $V_{GS} - V_T$ .

Ideal equation  $I_D = \frac{\beta_n}{2} (V_{GS} - V_{Tn})^2$  is not entirely accurate because pinch-off point under gate is influenced by  $V_{DS}$ . This influence of  $V_{DS}$  on pinch-off *essentially* modifies the length of the channel (channel length modulation effect).

## New equation for Saturation

$$I_D = \frac{\beta}{2} (V_{GS} - V_{Tn})^2 (1 + \lambda V_{DS})$$

$\lambda$  in SPICE is called LAMBDA, and is the channel length modulation factor. Empirical values range from (0.02 to 0.005)  $V^{-1}$ .

If we rewrite our current equation as

$$I_D = \frac{K'}{2} \frac{W}{L} (V_{GS} - V_{Tn})^2 (1 + \lambda V_{DS})$$

then when  $\lambda > 0V^{-1}$ , the effective channel length is reduced. Be careful not to confuse channel length with gate length. In saturated pinch-off, they are *not* equal!